

Fig. 1

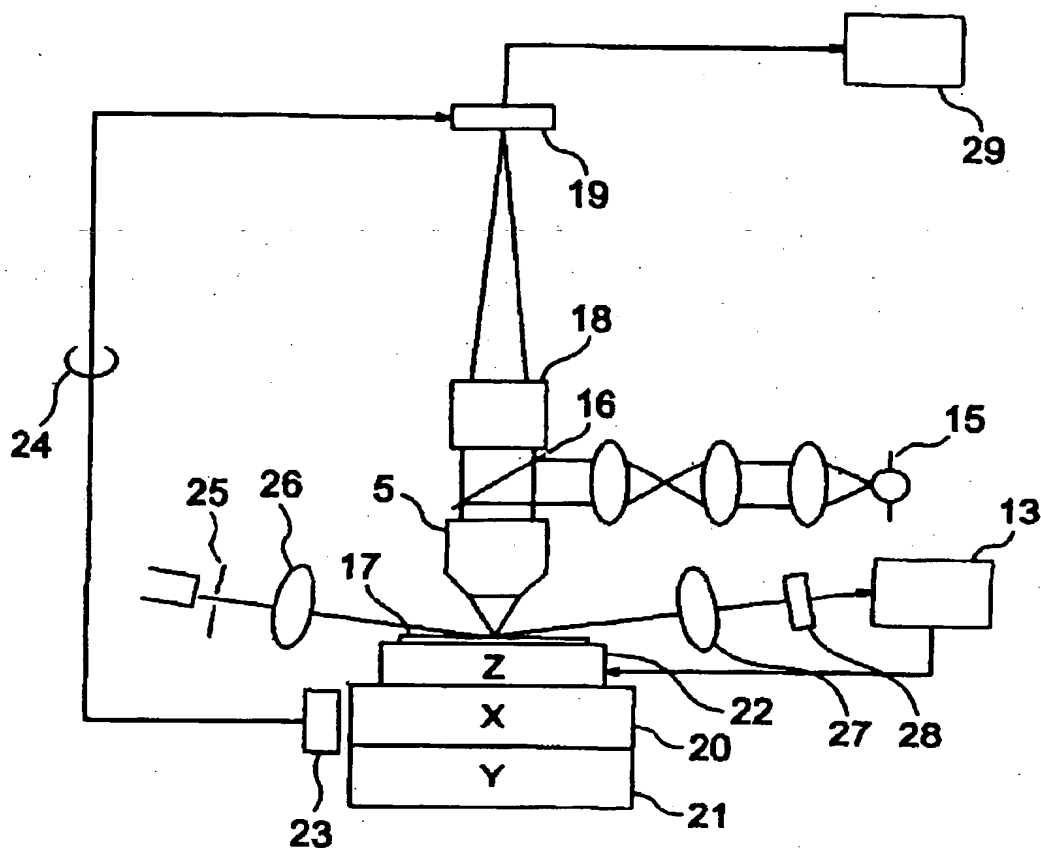
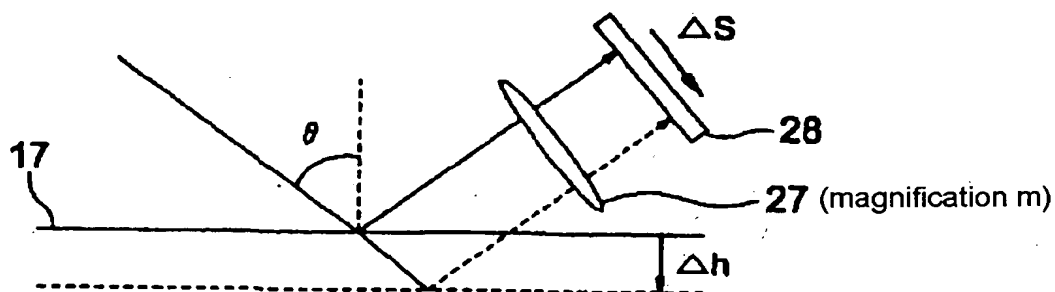


Fig. 2



Applicant: Atsushi Shimoda, et al.

I : Method and Apparatus for Inspecting Defects..

Atty Docket No. 16869P-031800

Sheet 2 of 15

Fig. 3

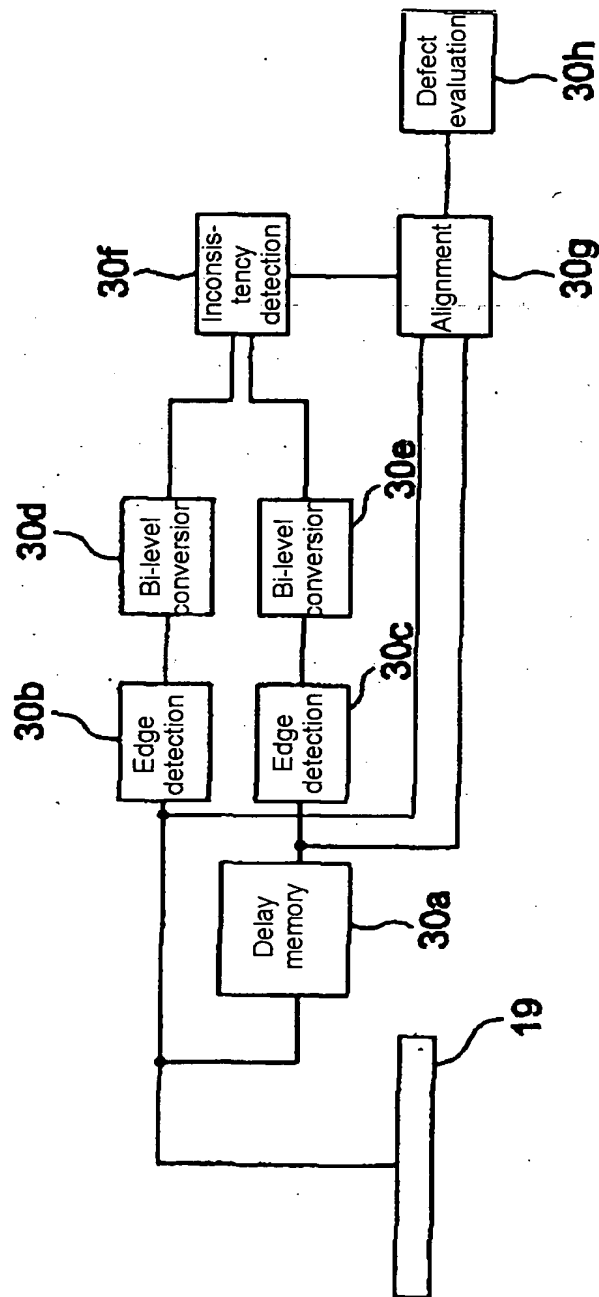
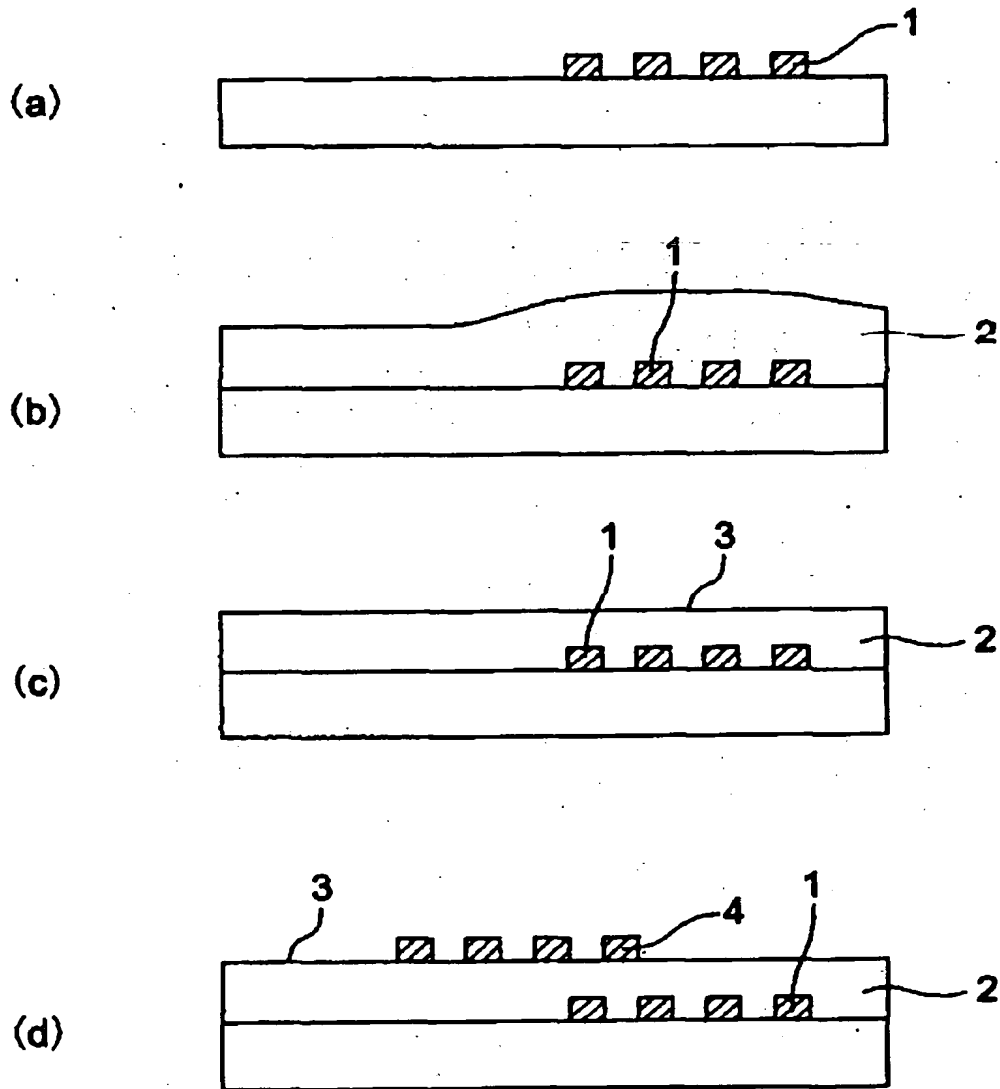


Fig. 4



Applicant: Atsushi Shimoda, et al.

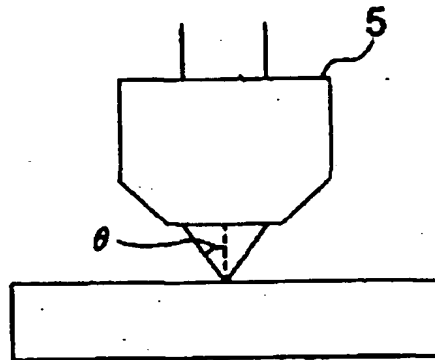
Title: Method and Apparatus for Inspecting Defects

Atty Docket No. 16869P-031800

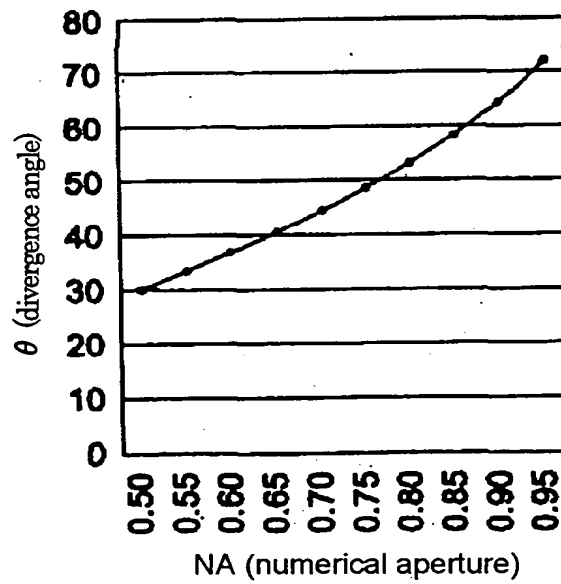
Sheet 4 of 15

Fig. 5

(a)



(b)



Applicant: Atsushi Shimoda, et al.

Title: Method and Apparatus for Inspecting Defects

Atty Do ket No. 16869P-031800

Sheet 5 of 15

Fig. 6

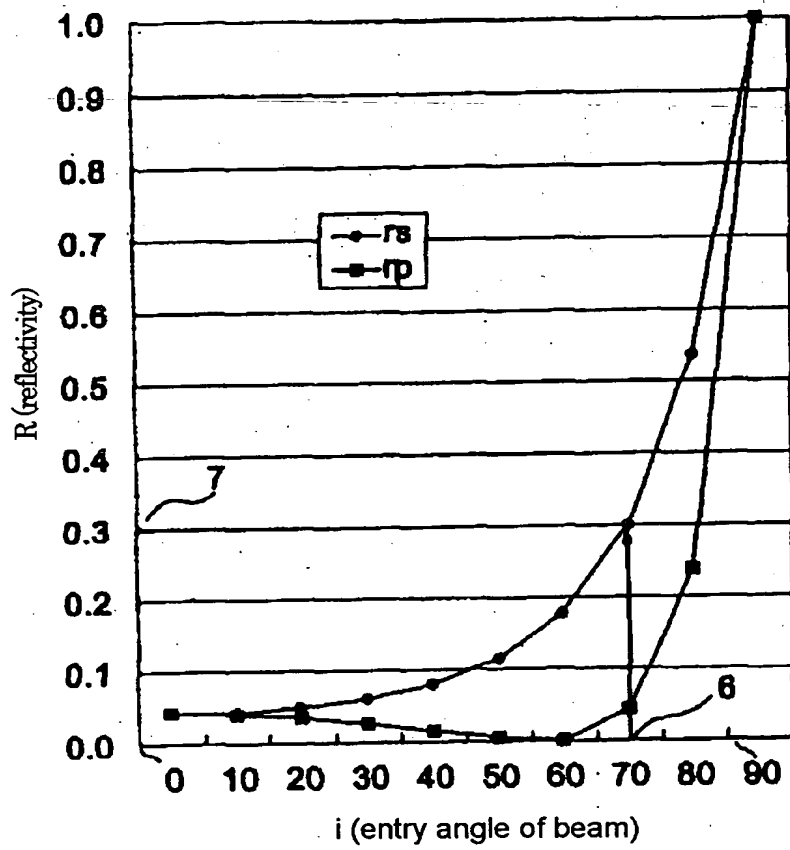


Fig. 7

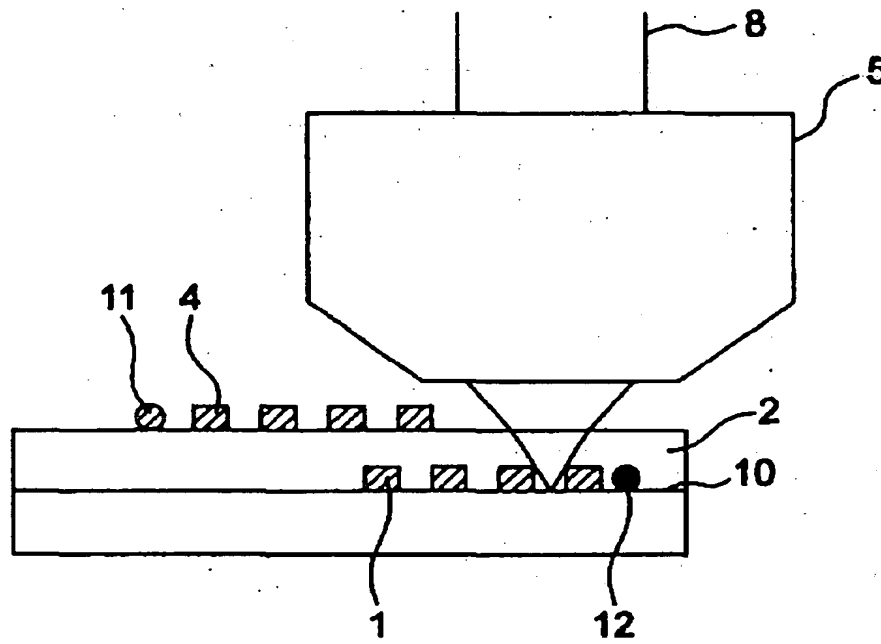


FIG. 7

Applicant: Atsushi Shimoda, et al.  
 Method and Apparatus for Inspecting Def cts...  
 Atty Dock t No. 16869P-031800  
 Sh et 7 of 15

Fig. 8

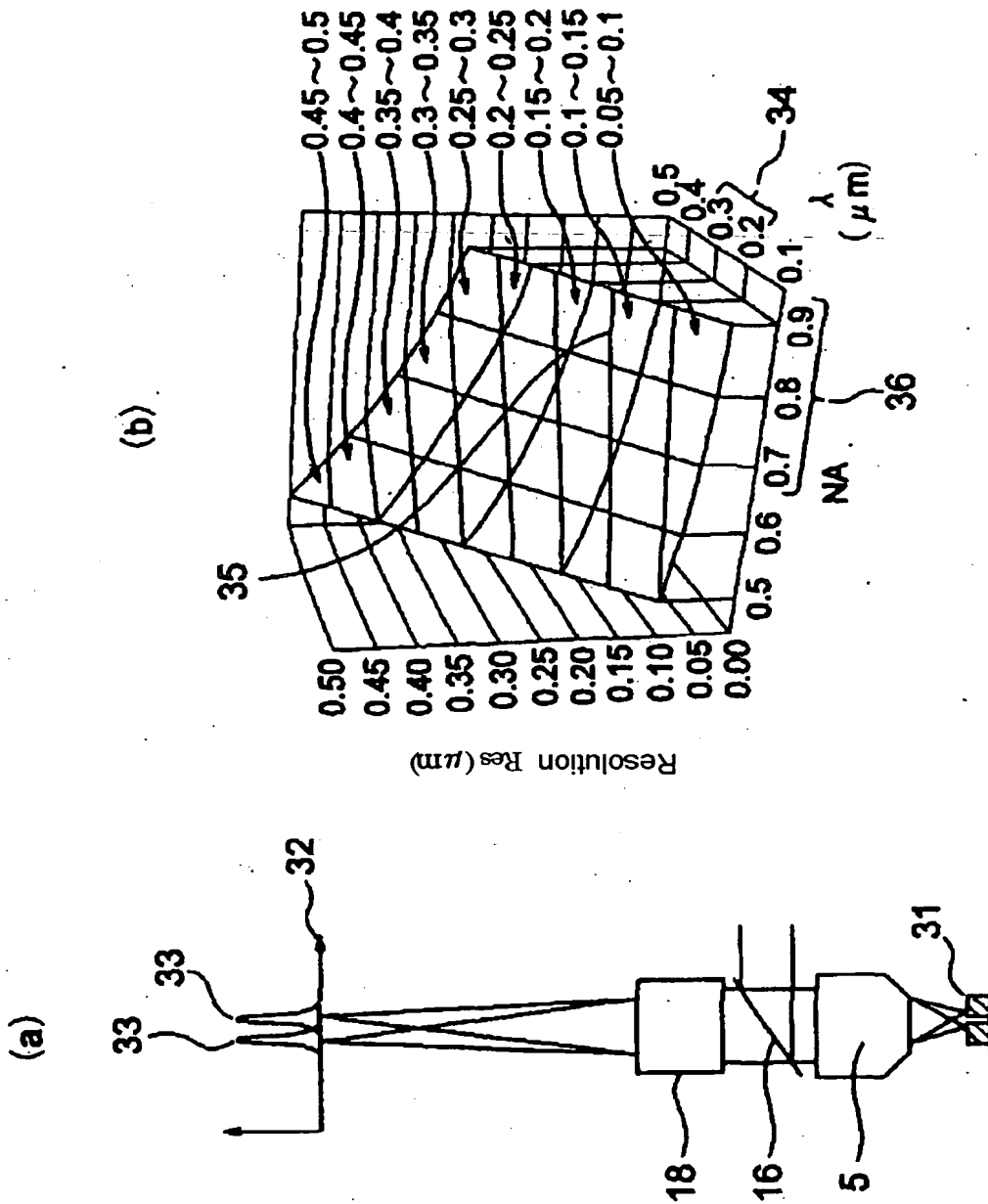


Fig. 9

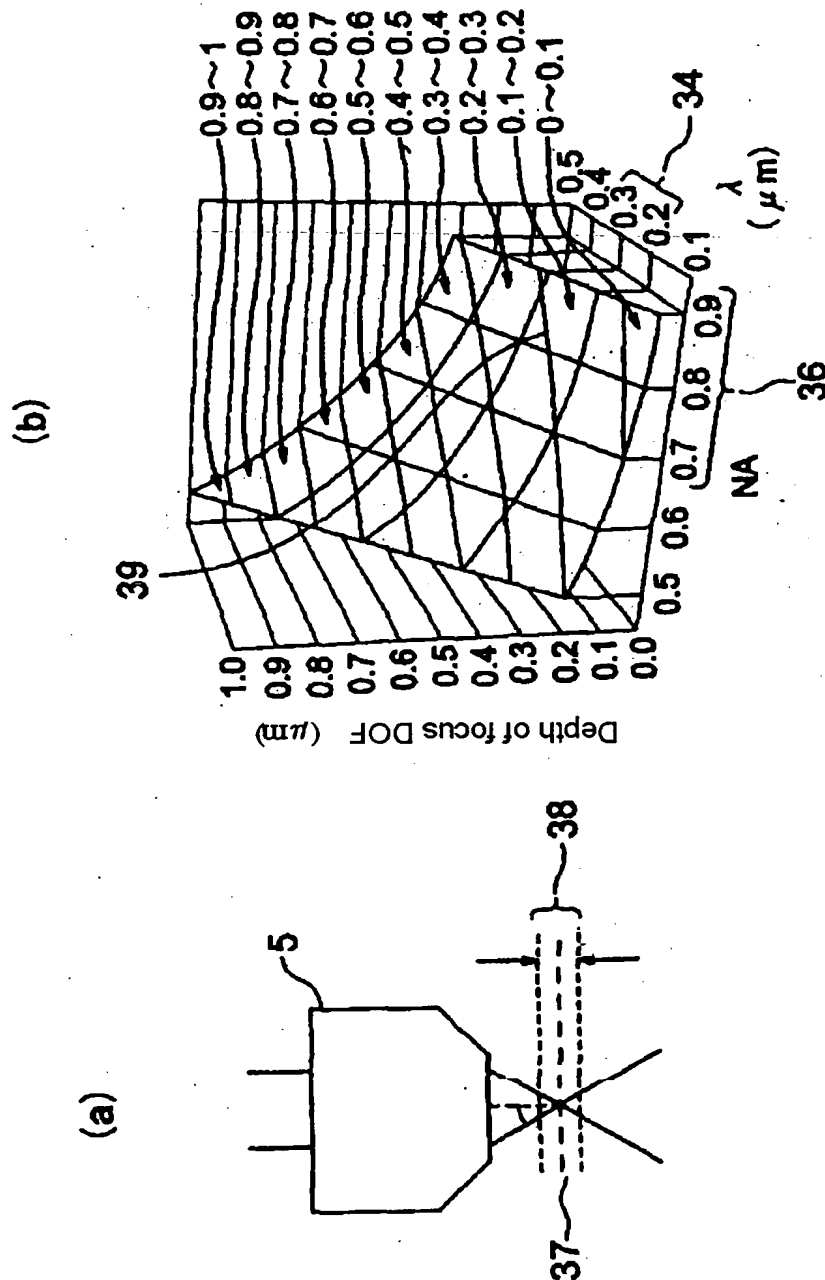
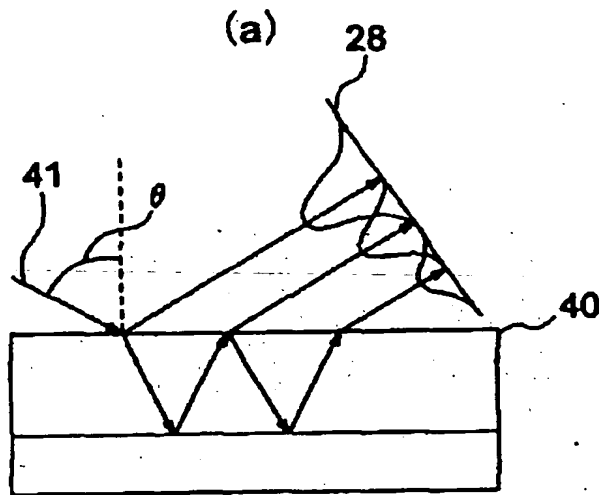
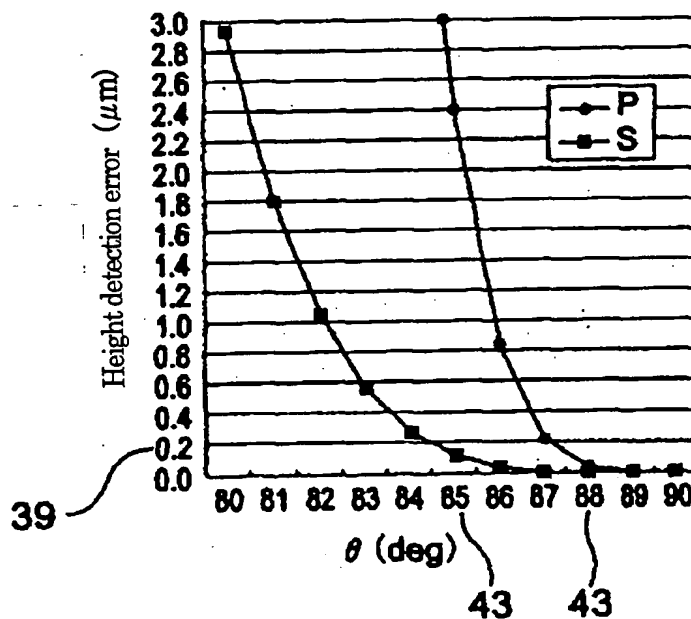




Fig. 10



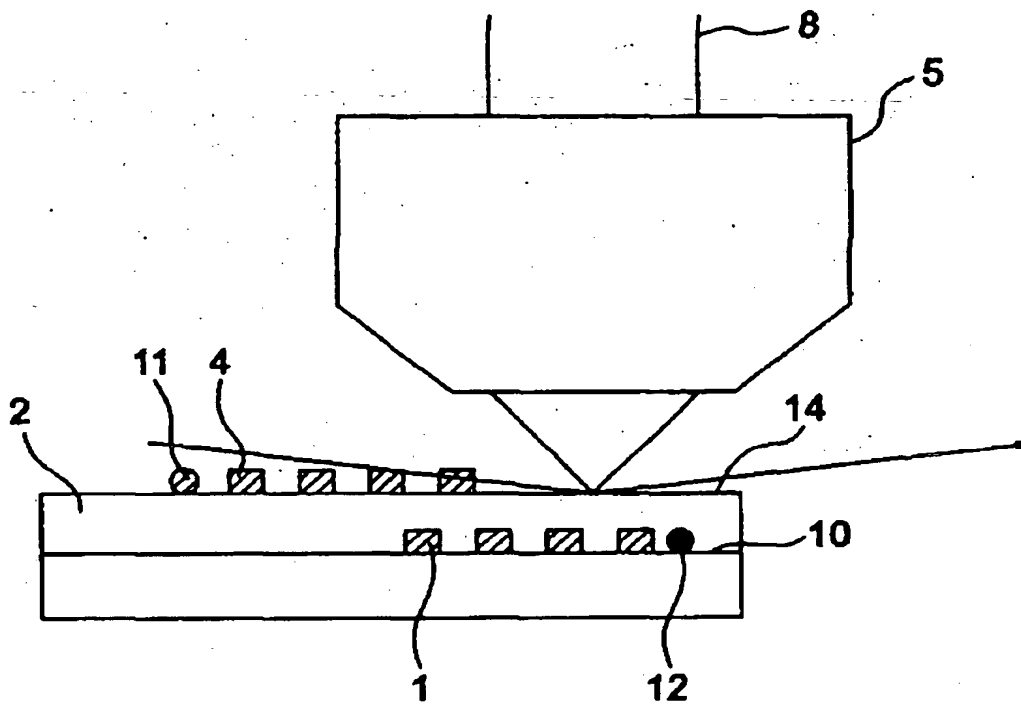
(b)



### 3. Method and Apparatus for Inspecting Defects...

She t 10 of 15

Time	Location	Activity	Remarks
0800	Field	Planting	Planted 100 seedlings
0900	Field	Planting	Planted 100 seedlings
1000	Field	Planting	Planted 100 seedlings
1100	Field	Planting	Planted 100 seedlings
1200	Field	Planting	Planted 100 seedlings
1300	Field	Planting	Planted 100 seedlings
1400	Field	Planting	Planted 100 seedlings
1500	Field	Planting	Planted 100 seedlings
1600	Field	Planting	Planted 100 seedlings
1700	Field	Planting	Planted 100 seedlings
1800	Field	Planting	Planted 100 seedlings
1900	Field	Planting	Planted 100 seedlings
2000	Field	Planting	Planted 100 seedlings
2100	Field	Planting	Planted 100 seedlings
2200	Field	Planting	Planted 100 seedlings
2300	Field	Planting	Planted 100 seedlings
2400	Field	Planting	Planted 100 seedlings



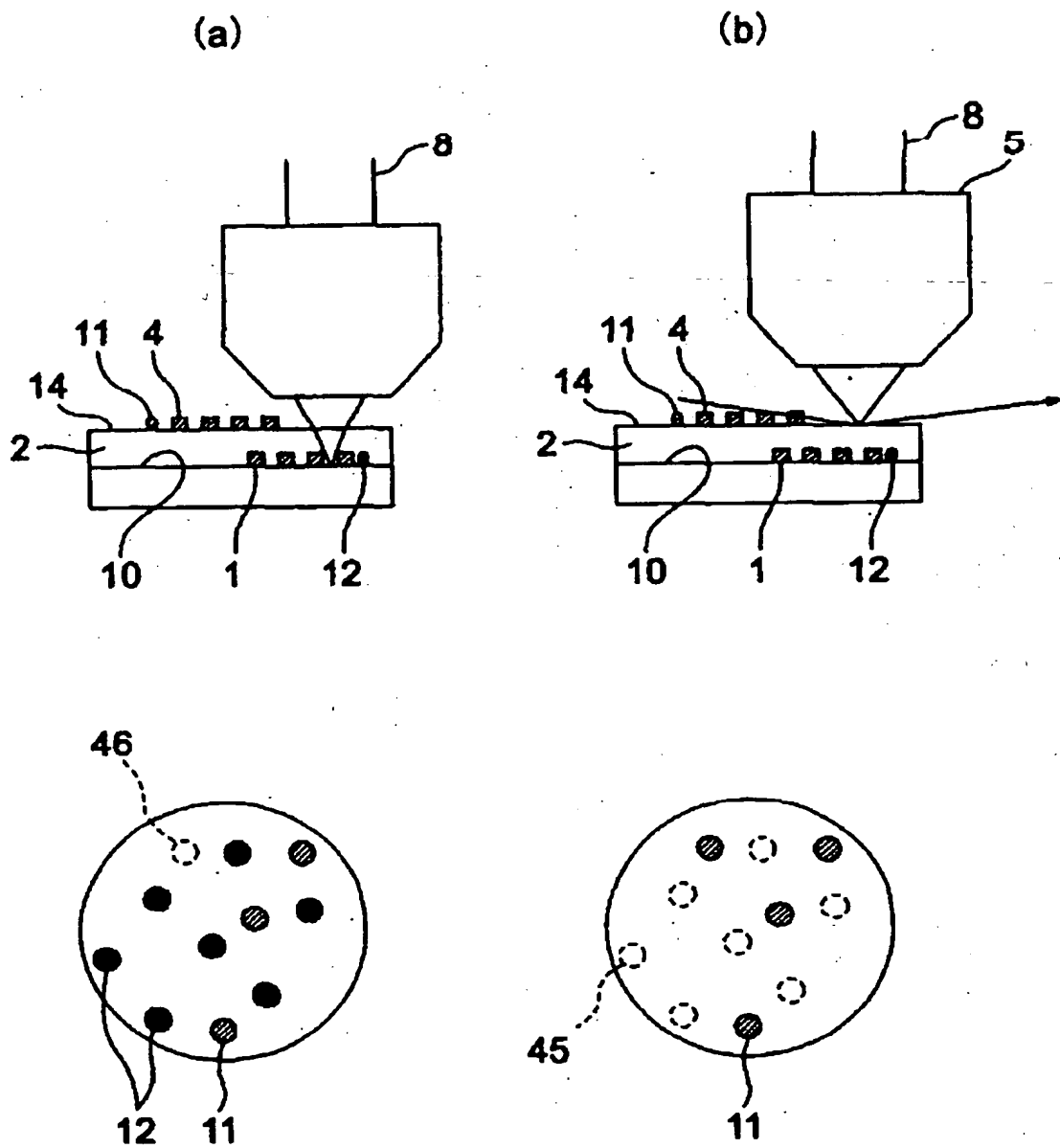
Applicant: Atsushi Shimoda, et al.

le: Method and Apparatus for Inspecting Defects.

Atty Docket No. 16869P-031800

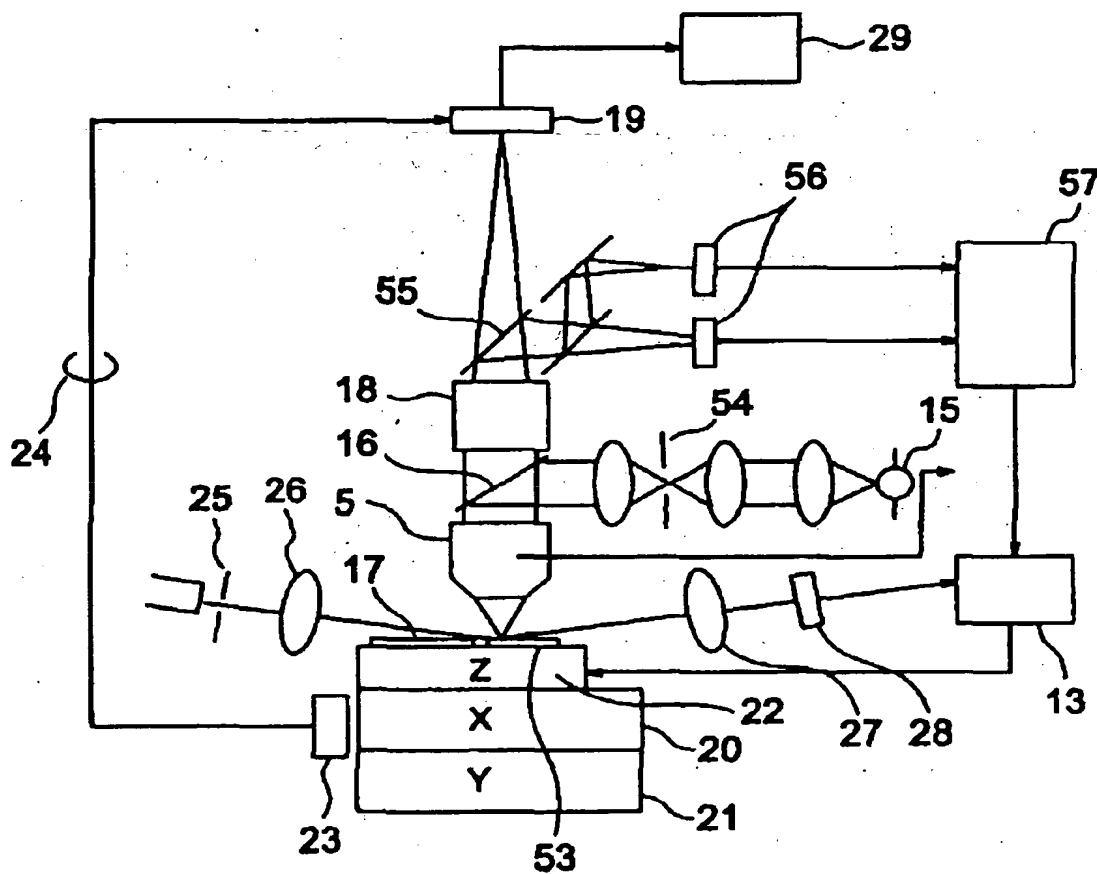
Sh et 11 of 15

Fig. 12



A schematic diagram of a laser scanning system. A laser source (24) emits a beam through a series of mirrors and lenses (25, 26, 17, 16, 18, 19) to illuminate a mask (5) on a stage (20). The stage is mounted on a Z-axis (21) and is moved by a motor (23). The mask is scanned by a scanning unit (13) which includes a mirror (15) and a lens (16). The scanning unit is controlled by a control unit (29) and a motor (27). The mask is also moved by a motor (28) along the X-axis (20) and Y-axis (21). The mask is labeled with 'Z', 'X', and 'Y' axes.

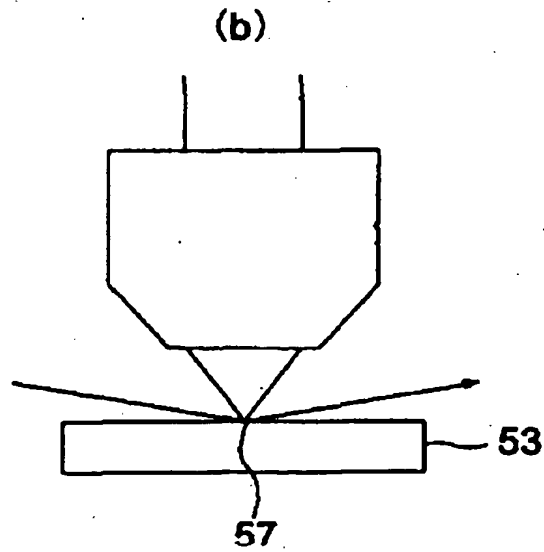
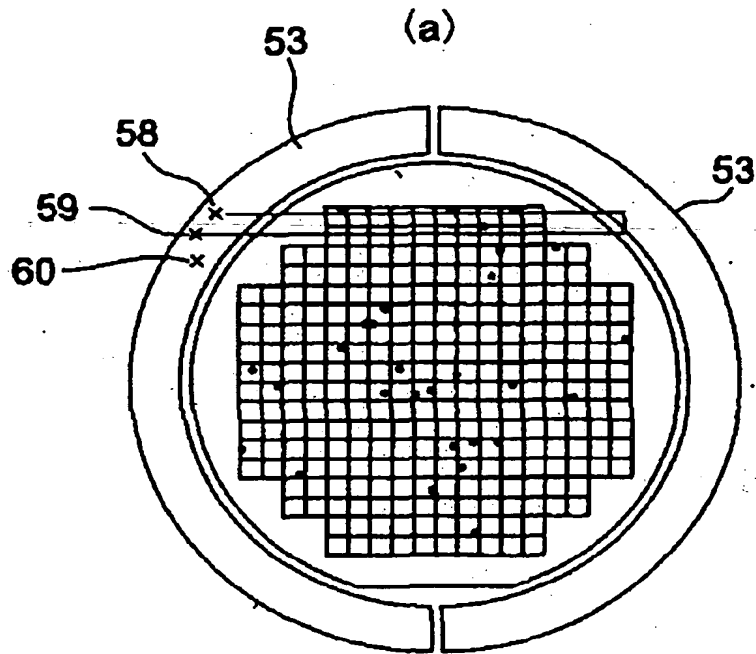
Fig. 15



**Title:** Method and Apparatus for Inspecting Defec

Sheet 14 of 15

**Fig. 16**

[illegible]

Applicant: Atsushi Shimoda, et al.

e: Method and Apparatus for Inspecting Defects..

Atty Docket No. 16869P-031800

Sheet 15 of 15

Fig. 17

